# User Guide to Operating the JSM-6510LV SEM

By Susheng Tan

Nanoscale Fabrication and Characterization Facility, Petersen Institute of NaoScience and Engineering, University of Pittsburgh, 348 Benedum Hall, 3700 O'Hara Street, Pittsburgh, PA 15261

Office: M104 Benedum Hall; Phone: (412) 383-5978; Email: sut6@pitt..edu

## I. Start the ChamberScope 🚨



## II. Start the SEM Main Menu 🚆

## III. User Login

- 1. Click the *User Login* of the operation menu tab.
- 2. Click the *Logon / Log off* button.
- 3. Select a user name from the user list, and click the *Log On* button.

## IV. Specimen Exchange

## 1. Prepare a specimen.

- Set the specimen on the specimen support, and adjust the specimen support so that the top of the specimen surface becomes in a same level with holder top.
- Be sure to fasten the specimen so that the top of the specimen surface does not protrude above the holder top.
- For such specimen as not electrically conductive, use a conductive paint to prevent the specimen from charging.
- Avoid setting the specimen containing unnecessarily water or oil, because it will contaminate inside the column.

## 2. Vent the specimen chamber.

- a. Click the HT icon to change it to OFF
- b. Click Sample Setting of the operation menu tub.
- c. Click the **Removing the specimen** button.
- d. Click the **VENT** button.
  - <u>Use slow venting for samples such as powders which are easily scattered. First select **Slow** and then click the **VENT** button.</u>
- e. After the light of the **VENT** button turns **ON**, the stage can be withdrawn to remove the specimen holder.

## 3. Setting the specimen.

- a. Click the **Setting** button.
- b. If the specimen protrudes above the holder, make sure to input the protruding sample height above the holder in the dialog box.
- c. Set the specimen holder onto the specimen stage.

## 4. Choose a recipe.

- a. Click the **Choose a recipe** button.
- b. From the displayed list of **Standard** recipe, select a recipe applicable to the sample, and click it. <u>If you are not sure which recipe is applicable to the sample to be observed, select Universal.</u> <u>The standard observation conditions will be set.</u>
- c. The operation navigation is changed to the setup observation condition menu.

Jser Login	Sample Se	tting	Recipe	Image List	Setup
Install U	ser File				Log On
Backup l	Jser File				
Rename (	Jser File				
Delete Us	er Name	Susheng			
Add User File		Mike Susheng			
		User List			
Log on /	Log off				

d. Set observation conditions according to the questions you will be asked. <u>If the specimen is not electrically conductive, not coated and High Vacuum is being selected,</u> <u>Acc. voltage is automatically set at 1kV.Under this condition EDS analysis question becomes</u> graved out, because the amount of signals for EDS analysis is insufficient.

e. Click the **OK** button. The observation condition will be set.

## 5. Evacuate the specimen chamber.

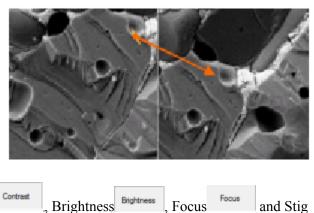
- a. Click the Evacuating the Chamber button.
- b. Close the specimen chamber, and click the **EVAC** button. Evacuation in the specimen chamber will start.
  - 1. If the sample without coating or containing water is observed as it is, the vacuum mode must be set to the low-vacuum mode.
  - 2. *After the mode is selected, a message will appear. Follow the instructions in the message to change the vacuum mode.*

#### V. Observing a Specimen

- 1. Click the HT icon to get HT ON
- 2. Click the (1), the (2) and the (2) icons to observe the image.
- Move view of interest to the center of main screen with <u>Click center</u>. <u>Double-click the left mouse button at any</u> <u>position in main screen. The double-clicked</u> <u>position moves to the center of the screen.</u>

4. set it at necessary magnification.

5. Adjust the image quality by using the Contrast (X, Y) Stig X Stig Y buttons.



## Notes: Observation Condition:

#### A). Difference of image quality depending on the value of the accelerating voltage

Generally, the more fine structure of the specimen surface appears when using a low accelerating voltage than using a high accelerating voltage.

## **B). Effect of the probe current**

You can obtain the higher magnification and the higher resolution for the SEM image, the smaller the probe diameter (*spot size*) to irradiate the specimen. However, the S/N (signal/noise) ratio depends on the probe current to irradiate the specimen. If you want to decrease the probe diameter, the probe current decreases. Therefore, you must select a probe current according to the magnification and the observation condition (such as the accelerating voltage and specimen tilt).

#### C). Effect of the working distance (WD) on the image

When you change the working distance (WD), in the short WD, although the depth of field becomes shallow, you can obtain high resolution; on the contrary, in the long WD, although the resolution decreases, the depth of field becomes deep. Moreover, in order to obtain a more optimum image quality, the brightness adjustment, astigmatism correction adjustment and focus adjustment become of importance.

#### D). Observation of the nonconductive specimen and charge up

When you irradiate a large current (high accelerating voltage and large spot size) electron beam on a nonconductive specimen, sometimes, electrons accumulate, in other words, charge up on the specimen. For such a specimen, you can reduce the charge-up to observe the specimen by using a low accelerating voltage or the low vacuum (LV) mode. Also, you can increase the emitted electrons by tilting the specimen, resulting in reducing the charge-up.

## VI. Operating the Image

VI. Oper	rating the	lmage				
	SEI	30kV	WD15mm	SS30 x75,000		
	Setting	the Signal:				
	1. Click t	the signal	EI, the accelerat	ting voltage <b>30kV</b> , working distance <b>WD15mm</b> , or spot		
	size SS	in the in	nage data display	/.		
	2. The re	levant settir	ng window is disp	played.		
	3. Double	e-click on th	ne desired setting	g in the list.		
	Signal	- 23 -	Acc. Voltage			
	SEI REF BEIW AUX		30.0kV 3.0kV 5.0kV 1.0kV 7.0kV	Spotsize		
			<b>*</b>	30 SS30 SS40 SS50 Set		
			ACB	0 50 99		
	🗾 SS Link	c	AF	· · ·		
	Signal	Data dian	lav			
	Signal         Data display           SEI         SEI (Secondary electron image)					
	BEIW BEC (Backscattered electr			<u> </u>		
	BET (Backscattered electro			<u> </u>		
				ron shadow image)		
	AUX	AUX				
	REF		lected electron in	mage)		
VII. S	Setting the	Scan Rate:	Scan1 Scan2 Scan3	3 Scan4 Photo Freeze		
ltem	Explan	ation		Note		
Scan 1		rching field o		You can select the averaging coefficient and scan rate. A		
Scan 2		ig image qua	-	exposure marker can be displayed.		
Scan 2	To observe the image.You can select the averaging coefficient and scan rate.To observe the image detail.You can select the averaging coefficient and scan rate.					
Scan 4				You can select the scan rate.		
	one at S	Scan 3 and a	cquire the image.			
Photo	image a	automatically		You can select the scan rate.		
Freeze	An observation image becomes the frozen image.			When you want to cancel Freeze, click one of any scan icons. When you want to return to the previous scan rate before Freeze, click the Freeze icon again.		

## VIII. Adjusting the Image Contrast/Brightness/Focus/Stig XY

Place a mouse pointer on the button, and operate as follows.

**Coarse adjustment:** While holding down the right button, move the mouse up (right) and down (left). **Fine adjustment:** While holding down the left button, move the mouse up (right) and down (left).

Colora Distance	-	0:- V	0. V	30	250	1000	10000	75000	
Contrast	Contrast Brightness Foo	Focus	Stig X	Stig Y		Mag -		Mag +	3

Adjusting the image magnification continuously by scrolling the middle mouse wheel.

## IX. Moving the Field View

1. Moving the stage in the vertical (Z) and tilt (T) directions: <u>use the ChamberScope to monitor Z</u> <u>and/or T to avoid crash the specimen into detector and/or lense</u>.

#### X. Observing the backscattered electron image

Features of backscattered electron images

- The brightness of the composition image becomes darker as the composition becomes lighter elements, and brighter as the composition becomes heavier elements.
- The topographic image looks like as if a light is illuminated from the right side of the specimen.
- For the convex part, the
- right side becomes bright and the left side becomes dark. For the concave part, the right and left sides become vice versa.
- Ite as if a light is infuminated from the right side of the specimen.

   Image: Composition image
- 1. Vent the specimen chamber, and then set a specimen.
- 2. Display a secondary electron image (SEI).
- 3. Click the signal **SEI** in the image data display.
- 4. Double-click the **BEIW** in the Signal setting window.
- 5. Click one of **Compo**, **Topo** and **Shadow** button in the BEI.
- At Shadow, the shadow level can set with the combo box (1 10, EX\_Ultra 3-dimensional impression). And, adjustment of the Gain can change to Auto (it can set automatically according to the Spotsize and Acc Voltage) or Manual (High, Medium, Low, Analysis).
- 6. Adjust the Contrast and/or Brightness to optimize the quality of the backscattered electron image.

Guideline of the obset vation condition					
	Criterion	Tendency	Caution		
WD	10 - 20mm	Image is brighter at shorter WD	Take care lest detector hits sample		
Accelerating voltage	15 - 20kV	Image is brighter at higher accelerating voltage	Some sample are damaged by electron beam		
Spotsize	30 - 50	Image is brighter at larger spotsize	Same as above		
Movable aperture	1 or 2	Image is brighter at 2.			

## **Guideline of the observation condition**

#### XI. Tilt correction

If the focus is not adjusted at both edges of the field of view for a tilted specimen, adjust the focus using the slide bar.

- 1. Adjust the focus at the center of the Live image.
- 2. Click the Tilt icon  $\square$ , or select Menu bar Tools  $\rightarrow$  Tilt Correction.
- 3. The Tilt correction menu is displayed.
- 4. Select the ON/OFF radio button in the Dynamic Focus or Mag. Correction to **ON**.
- 5. Click the Scan 3 icon  $\bigcirc$  or the Scan 4 icon  $\bigcirc$
- 6. Correct the focusing with the slide bar. Once the correction is performed, the amount of correction remains stored in the memory, even if you set the ON/OFF button to **OFF**.

0	0	ON OFF MAX
1		100.01
		,
	00	ON 💿 OFF
1		MAX
	1	0 0

## Low Vacuum Mode Observation

- 1. Set a specimen.
- 2. Click the **Low Vacuum** button in the Vacuum . The vacuum mode is switched from high vacuum to low vacuum, and starts evacuating the specimen chamber.
- 3. Set the accelerating voltage to 15 kV.
- 4. Set the pressure of the specimen chamber to 30 Pa. or the value you desired from the pressure values combo box, and click the Start button. The Start button switches to Stop, and it starts flashing. When the pressure reaches to selected value, the flashing stops.
- 6. Set the spot size to 30 60.
- 7. Switch the Signal to **BEIW**, and click the **Shadow** button.
- 8. Set the shadow level to **1**.
- 9. Click the HT icon to get HT ON
- 10. Click the Scan1 icon Scan1

VENT EVAC 100Pa 110Pa 10Pa Low Van Signal BEI SEI REF BEIV Compo Торо Shadow AUX 1 Gain Auto -SS Link

Vacuum Status

Draw Out

Arlock

- 11. Click the state the image.
- 12. Adjust the image quality by using the Contrast, Brightness, Focus and Stig (X, Y) buttons.
- 13. Increase the magnification by four steps, and check to see the image whether or not a charge up occurs on the specimen. If the charge up occurs on the specimen, increase the pressure of the specimen chamber or adjust the *Spotsize* so that the charge up disappears.

Table. Relationship between pressure, charge up and brightness

$Low \leftarrow$	Pressure	$\rightarrow$ High
Much ←	Charge up	$\rightarrow$ Few
Bright $\leftarrow$	Brightness	$\rightarrow$ Dark